

Practitioner's Docket No.: MUH-12818

RECEIVED  
CENTRAL FAX CENTER

MAY 25 2006

CERTIFICATION OF MAILING OR TRANSMISSION

I hereby certify that this correspondence is being deposited with the United States Postal Service with sufficient postage as first class mail in an envelope addressed to the Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450 or facsimile transmitted to the U.S. Patent and Trademark Office on the date shown below.

  
Laurence A. GreenbergMay 25, 2006  
DateIN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Application No. : 10/675,049 Confirmation No.: 5871  
Filing Date : September 30, 2003  
Applicant : Ioannis Dotsikas  
Title : Method and Furnace for the Vapor Phase  
Deposition of Components onto  
Semiconductor Substrates with a  
Variable Main Flow Direction of the  
Process Gas :  
TC/AU : 2818  
Examiner : Duang A. Le  
Customer No. : 24131

SUPPLEMENTAL AMENDMENT

Mail Stop Fee Amendment  
Hon. Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

S i r :

Supplemental to the amendment filed May 15, 2006, and  
responsive to the Office action dated February 16, 2006,  
kindly amend the above-identified application as follows:

Amendments to the Claims are reflected in the listing of  
claims which begins on page 2 of this paper.

05/26/2006 TL0111 00000032 10675049

Remarks/Arguments begin on page 9 of this paper.

100.00 OP